

PATENT

Atty. Dkt. No. AMAT/2981/CPES/ESPD/PJS

IN THE CLAIMS:

Please cancel claims 5, 22, 30, 108, and 109 and amend the claims as follows:

1-41. (Canceled)

42. (Previously Presented) An apparatus for processing a substrate, the apparatus comprising a pump having a plurality of inlet ports, a first inlet port provided to evacuate gas from a first chamber or first pump, and a second inlet port provided to evacuate gas from a second chamber or second pump, the pump abutting at least one of the chambers.

43-49. (Canceled)

50. (Previously Presented) An apparatus for processing a substrate, the apparatus comprising a multiple inlet pump having a first inlet port in a first inlet stage, and a second inlet port in a second inlet stage, the first inlet port provided to evacuate gas from a first chamber or first pump, and a second inlet port provided to evacuate gas from a second chamber or second pump, the multiple inlet pump abutting at least one of the chambers.

51-58. (Canceled)

59. (Previously Presented) An apparatus for processing a substrate, the apparatus comprising:

(a) a plurality of chambers that are shaped and sized to hold one or more substrates; and

(b) a pump having a first inlet port in a first inlet stage, and a second inlet port in a second inlet stage, the first inlet port provided to evacuate gas from one chamber and a second inlet port provided to evacuate gas from another chamber, the pump abutting at least one of the chambers.

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60-109. (Canceled)

110. (Previously Presented) An apparatus for processing a substrate, the apparatus comprising:

a chamber; and

a pump abutting the chamber, the pump having an inlet connected to the chamber to evacuate gas in the chamber and an outlet that exhausts the evacuated gas to atmospheric pressure, the apparatus further comprising a pressure controller to control the pressure of the gas in the chamber by adjusting a speed of the pump.

111. (Previously Presented) An apparatus for processing a substrate, the apparatus comprising:

a load-lock chamber comprising an enclosure; and

a pump abutting the load-lock chamber, the pump having an inlet connected to the load-lock chamber to evacuate gas from the load-lock chamber and an outlet that exhausts the gas to atmospheric pressure, the apparatus further including a pressure controller to control the pressure of the gas in the load-lock chamber by adjusting a speed of the pump.

112. (Previously Presented) An apparatus for processing a substrate, the apparatus comprising:

a process chamber comprising a support and a gas distributor; and

a pump system comprising a pre-vacuum pump abutting the process chamber, the pre-vacuum pump having an inlet connected to the process chamber to evacuate gas from the process chamber and an outlet that exhausts the evacuated process gas to atmospheric pressure, whereby a substrate held on the support is processed by process gas introduced through the gas distributor into the process chamber, the apparatus further including a pressure controller to control the pressure of the processed gas in the process chamber by adjusting a speed of the pre-vacuum pump.

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113. (New) The apparatus of claim 42, wherein the pump has a plurality of screw augers with interlacing blades.
114. (New) The apparatus of claim 42, wherein the pump has two or more rotors with interdigitated blades.
115. (New) The apparatus of claim 42, wherein the pump has a plurality of parallel shafts, each parallel shaft having a hook and claw mechanism.
116. (New) The apparatus of claim 50, wherein the multiple inlet pump has a plurality of screw augers with interlacing blades.
117. (New) The apparatus of claim 50, wherein the multiple inlet pump has two or more rotors with interdigitated blades.
118. (New) The apparatus of claim 50, wherein the multiple inlet pump has a plurality of parallel shafts, each parallel shaft having a hook and claw mechanism.
119. (New) The apparatus of claim 59, wherein the pump has a plurality of screw augers with interlacing blades.
120. (New) The apparatus of claim 59, wherein the pump has two or more rotors with interdigitated blades.
121. (New) The apparatus of claim 59, wherein the pump has a plurality of parallel shafts, each parallel shaft having a hook and claw mechanism.
122. (New) The apparatus of claim 110, wherein the pump has a plurality of screw augers with interlacing blades.

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123. (New) The apparatus of claim 110, wherein the pump has two or more rotors with interdigitated blades.

124. (New) The apparatus of claim 110, wherein the pump has a plurality of parallel shafts, each parallel shaft having a hook and claw mechanism.

125. (New) The apparatus of claim 111, wherein the pump has a plurality of screw augers with interlacing blades.

126. (New) The apparatus of claim 111, wherein the pump has two or more rotors with interdigitated blades.

127. (New) The apparatus of claim 111, wherein the pump has a plurality of parallel shafts, each parallel shaft having a hook and claw mechanism.

128. (New) The apparatus of claim 112, wherein the pump has a plurality of screw augers with interlacing blades.

129. (New) The apparatus of claim 112, wherein the pump has two or more rotors with interdigitated blades.

130. (New) The apparatus of claim 112, wherein the pump has a plurality of parallel shafts, each parallel shaft having a hook and claw mechanism.